

MOS Device: Basics

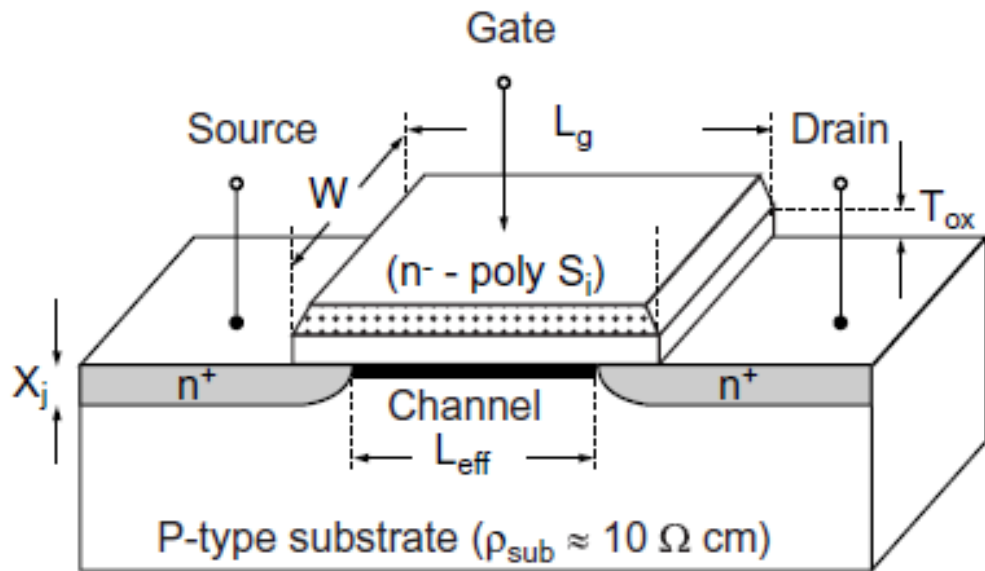
- MOSFET & Modeling -

Renesas Design Vietnam Co., Ltd.
Phuoc Tran, Nguyen Phuoc Nguyen, RVC Training Center

Lecture 3

October 11, 2010 Rev. 0.00

(5) MOSFET: Basic structure



Electrodes:

Source: Source of Electrons
(pin from which electron flows out)

Drain: Drain the Electron
(pin to which electron flows in)

Gate: Control gate for electron flow

Substrate: Fixed silicon substrate bias

Structural parameters:

Planar dimensions = L_g , L_{eff} , and W

Longitudinal dimensions = T_{ox} , X_j , and ρ_{sub}

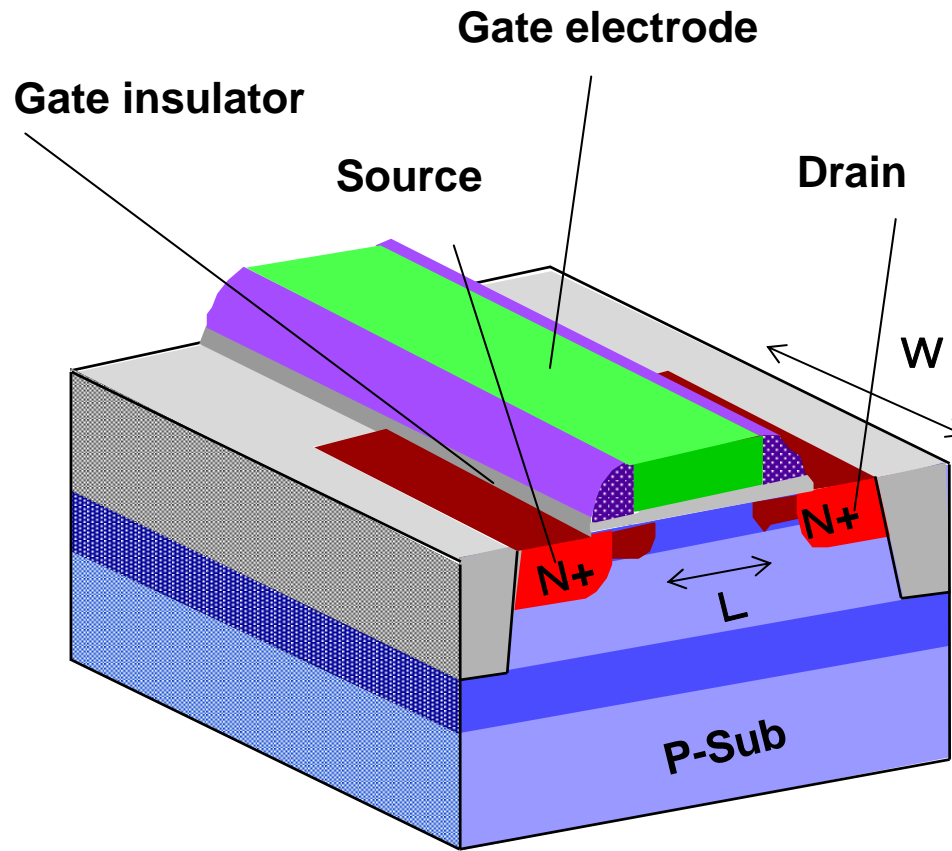
Operation:

The conductance between source and drain is controlled by the gate voltage.

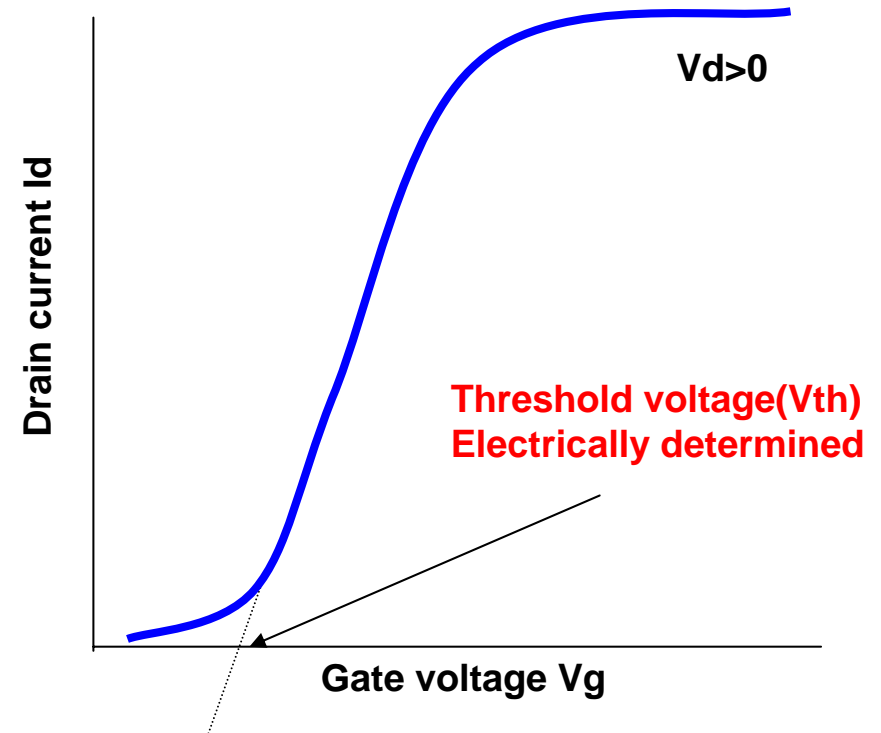
Features

- 1) Input impedance = completely capacitive. It allows direct circuit connection.
- 2) Utilization of silicon surface (channel) conduction. It gives easy to isolate devices, which is ideal as highly integrated LSI device.

MOSFET 3D-Image and Typical I-V Curve



L:Channel length
W:Channel width



$$V_{th} = \left(\phi_{MS} + \frac{Q_{ss}}{C_o} \right) + 2\phi_F + \frac{Q_B}{C_o}$$

How to Fabricate MOSFET; Photo-Lithography

Photolithography is the most important LSI process step.

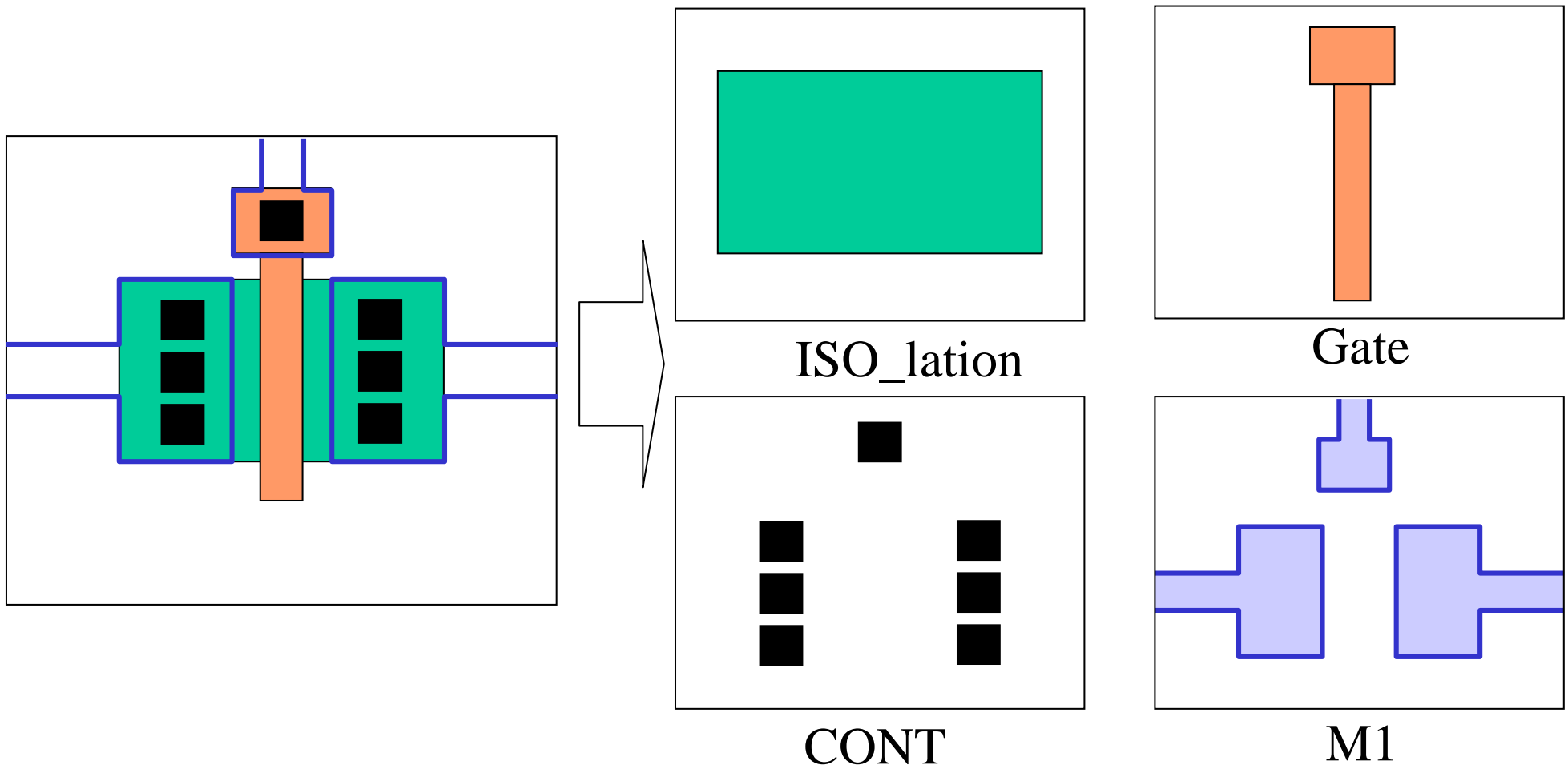
It is the same as photo printing process with Nega-film in optical photography.

In LSI process, we use Photo-mask instead of Nega-film.

Photolithography allows selective etching of layers or selective implant of impurities.

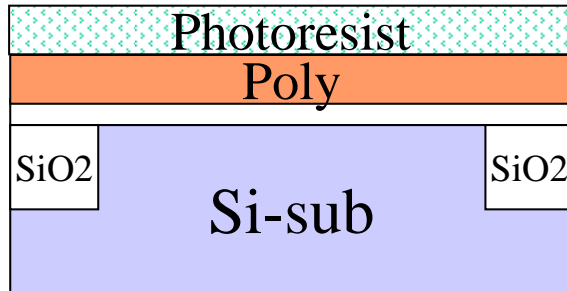
Example: Mask layout of NMOS

Four photo-masks for simplest NMOS design

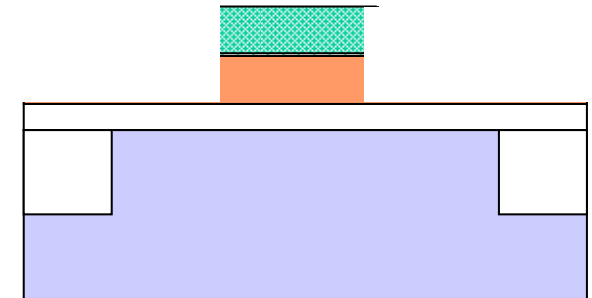


Key Process Flow; Changes in Sectional Structure

Gate Oxide
& Poly
deposition
Photoresist
coating



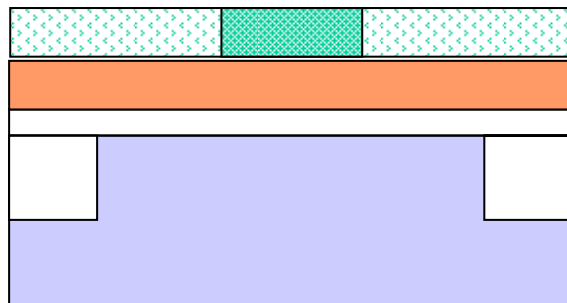
Development
& baking
& etch Poly



Mask
→

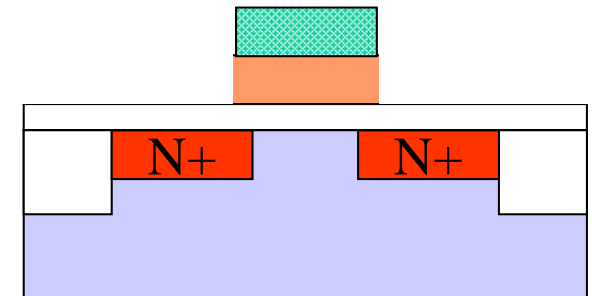
Ultraviolet light
↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓

Photolitho
With mask

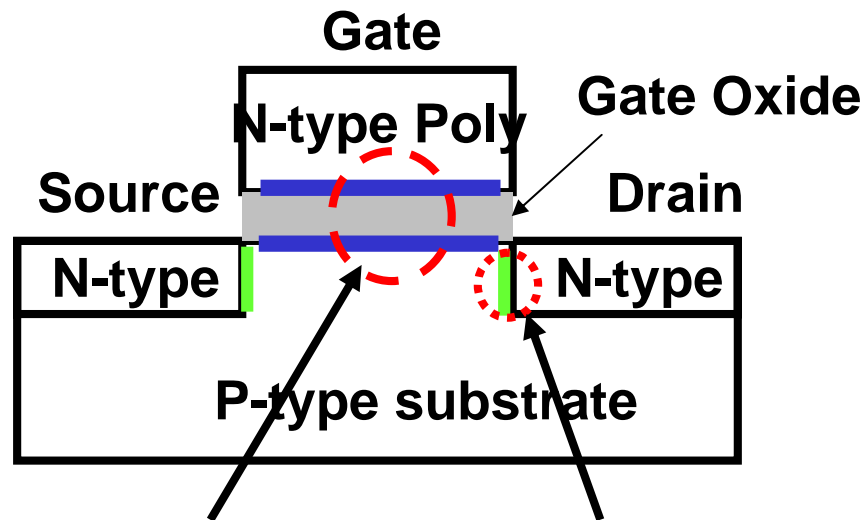


As Implant to
form Source and
Drain

As (N-Type Impurity) ion
↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓ ↓



Basic and Updated MOSFET structure



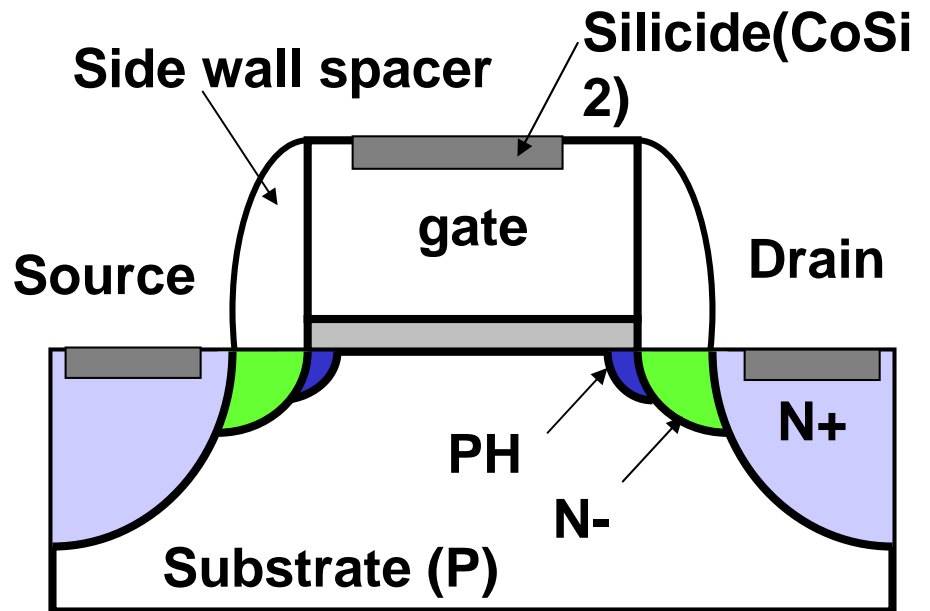
MOS capacitor

PN Junction

NMOS (Basic structure)

By applying voltage to gate, charges are induced at the capacitor.

The charges are pull out by Drain.



NMOS (Advanced structure)

N+: Diffusion layer(Highly doped N-type)

N-: Lower doped diffusion layer to relax the electric field at PN junction edge

PH: p-type diffusion layer to suppress short channel effect

MOSFET operation: I-V characteristics

There are three operational states:

Cut-off

Characteristic parameter = Threshold voltage V_{th}

Non-saturation (also called Linear)

Characteristic parameter = Pinch-off voltage V_{ds}'

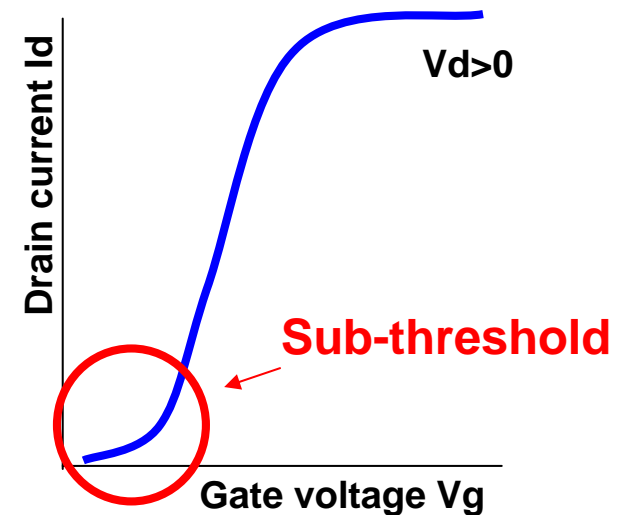
Saturation

If you close look at the “Cut-off bias condition”:

the small I_{ds} leak-current can be characterized in Sub-threshold bias condition.

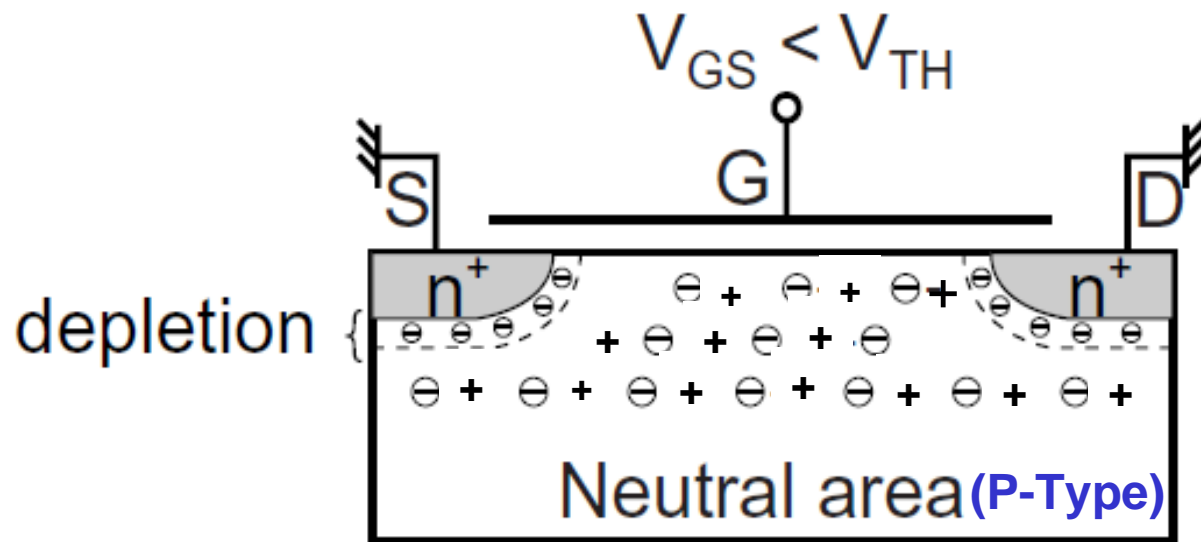
... **this leak-current is important.**

Since it determines CMOS leakage current! ... Limit low Pw operation.



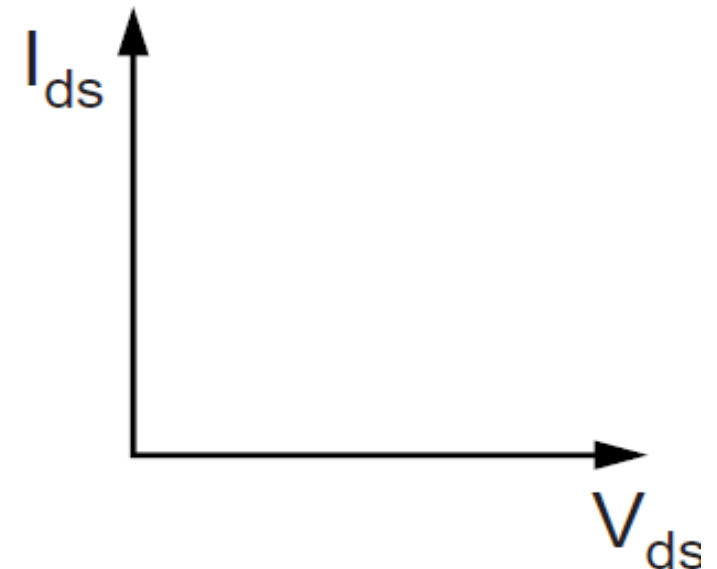
MOS Operation: Cut-off state

When $V_g < V_{th}$, no inversions at the surface, therefore no drain current I_{ds} flows between source and drain.



⊖; Fixed Bulk Charge, +; Hole

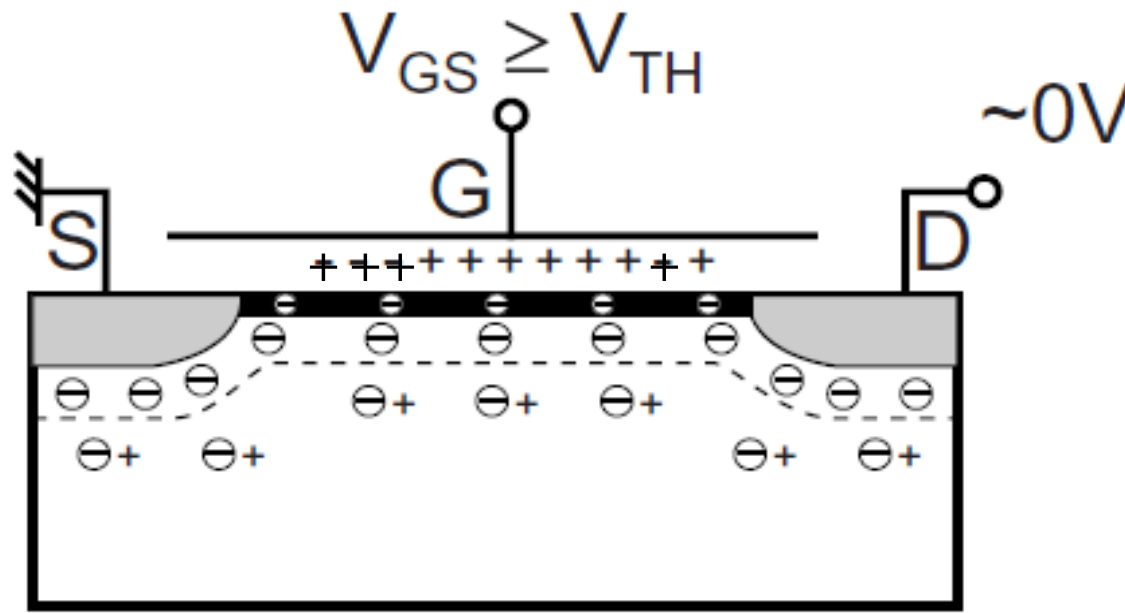
Charges and Channel



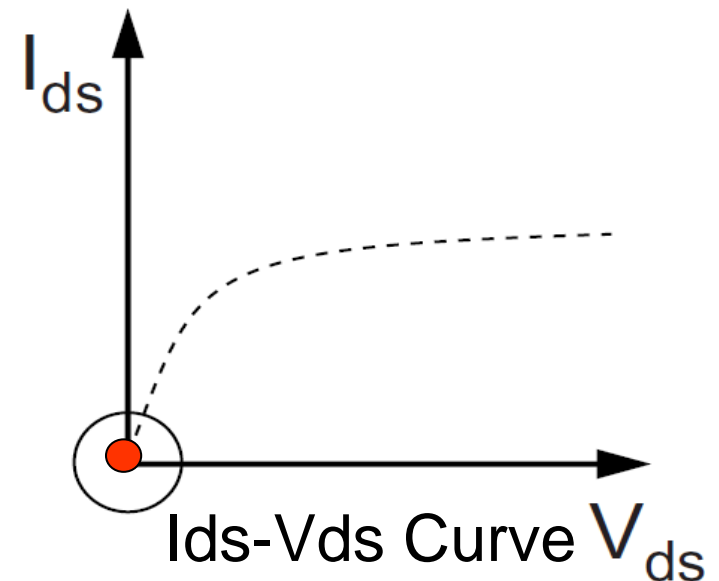
I_{ds} - V_{ds} Curve

MOS Operation: On state @ $V_{ds}=0V$

When $V_g > V_{th}$, positive charges at Gate induce electrons at Si surface, which form a conductive “channel” between source and drain.

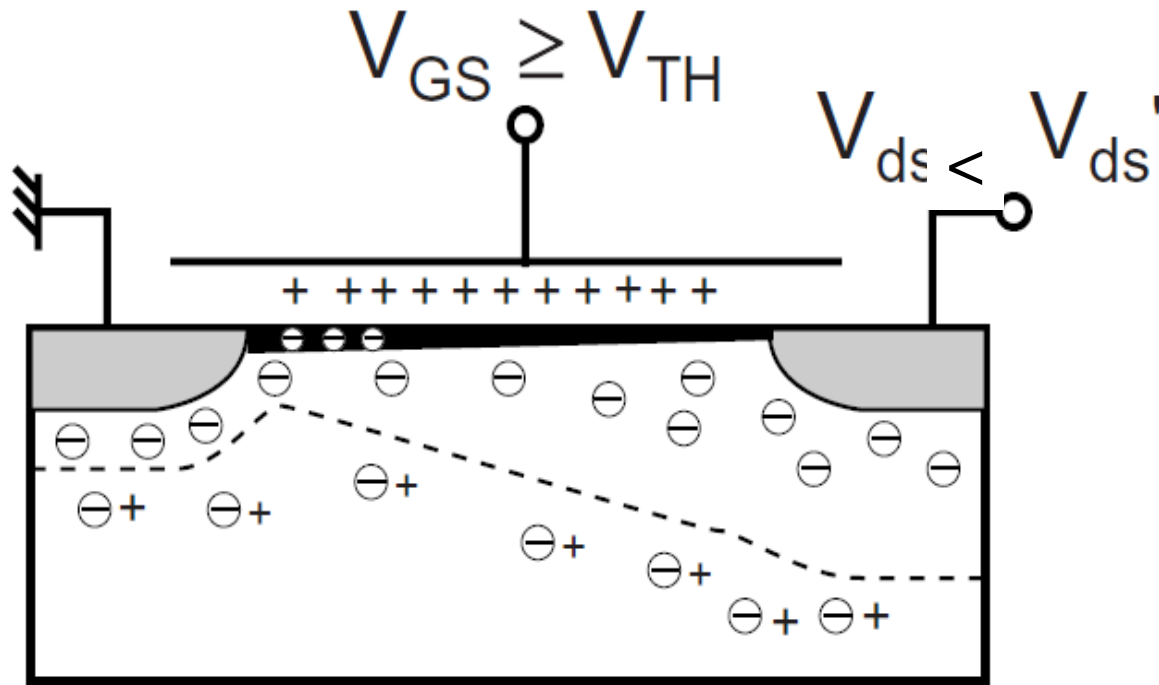


Charges and Channel

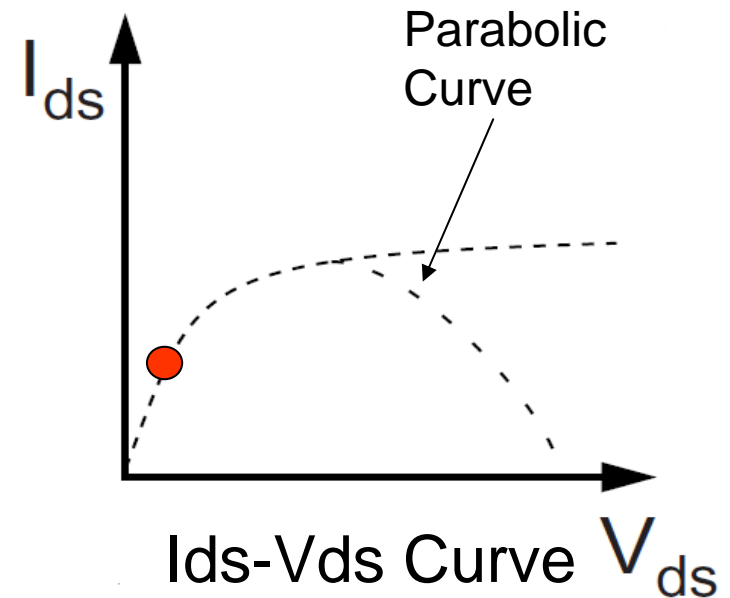


MOS Operation: non-saturation state

When $V_g > V_{th}$ and $V_{ds} > 0V$, I_{ds} start flowing through the channel. Channel depth near the drain becomes thin compared with that at source, because $Q_{nd} = C_{ox}(V_{gs} - V_{ds}) < Q_{ns} = C_{ox}(V_{gs} - V_s)$



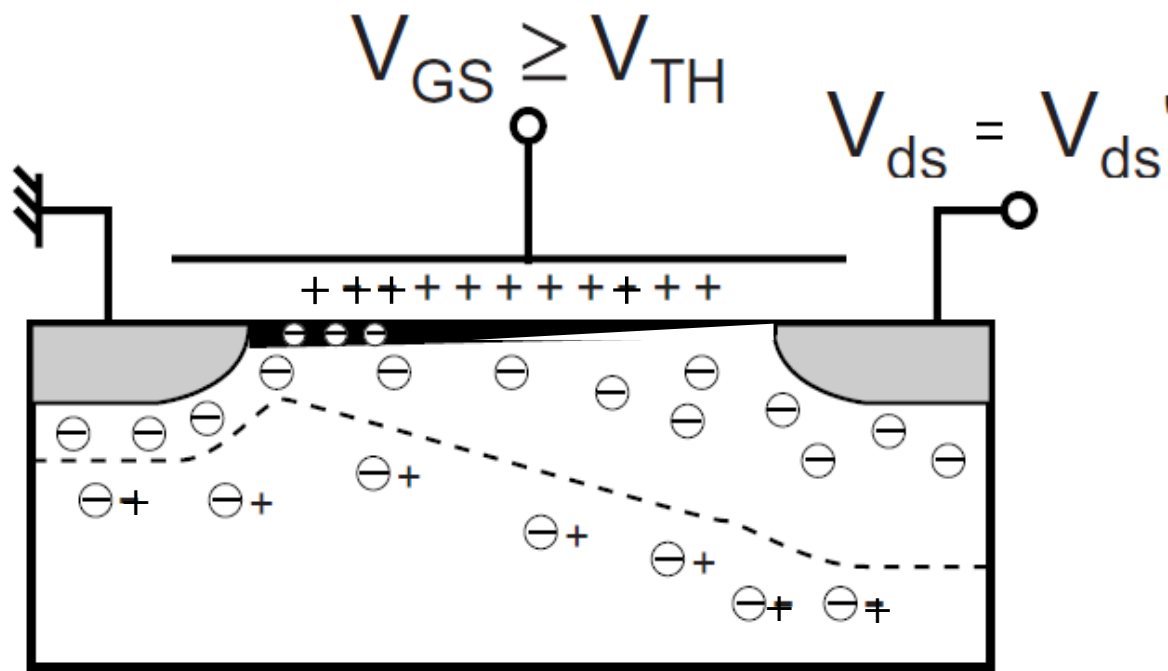
Charges and Channel



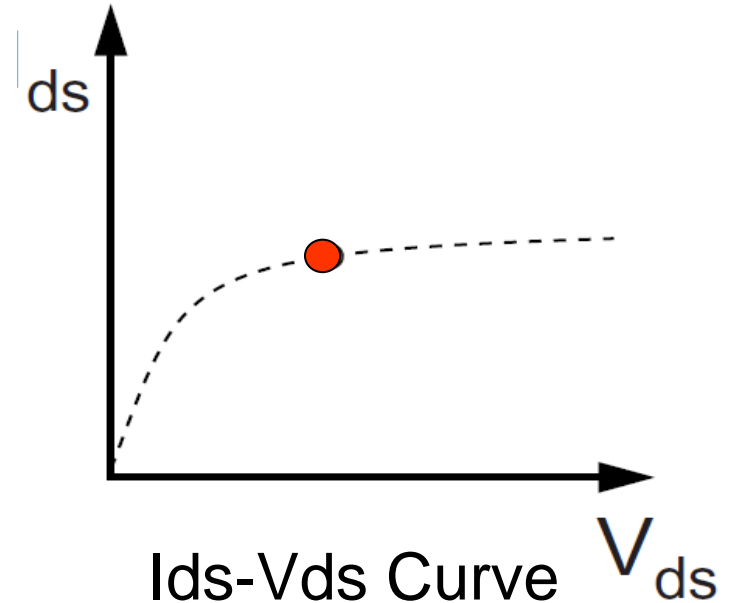
I_{ds} - V_{ds} Curve V_{ds}

MOS Operation: pinch-off state

When $V_g > V_{th}$ and $V_{ds} = V_{ds}'$ (pinch-off voltage), channel depth at drain-end is pinched-off (disappeared) because $Q_n = C_{ox}(V_{gs} - V_{ds}') = 0$!

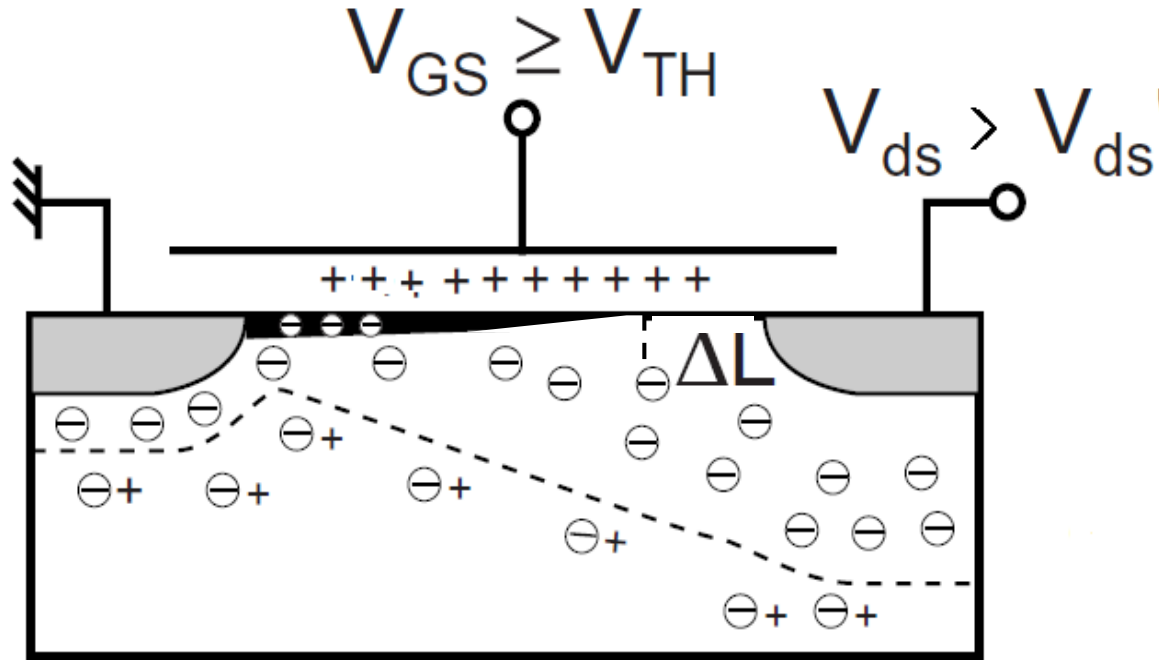


Charges and Channel

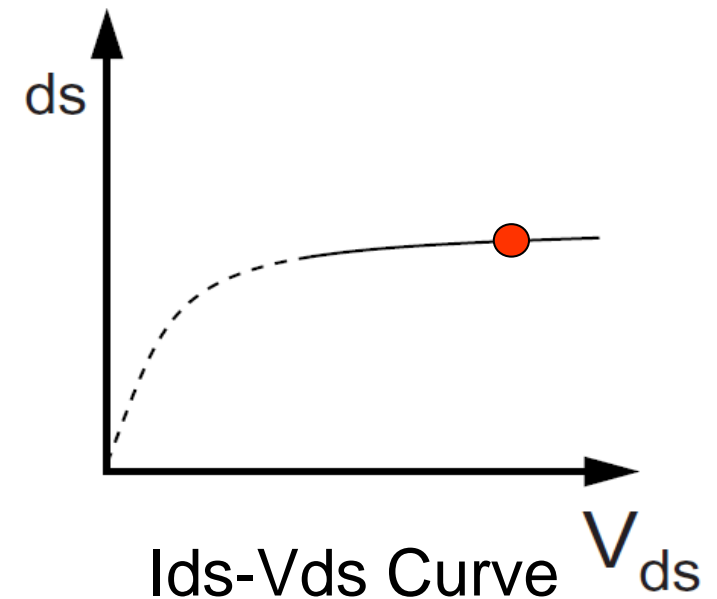


MOS Operation: saturation state

When $V_G > V_{th}$ and V_{ds} are biased above the V_{ds}' (pinch-off voltage), drain current are saturated with slightly increase due to channel shortening ΔL by high drain field effect.



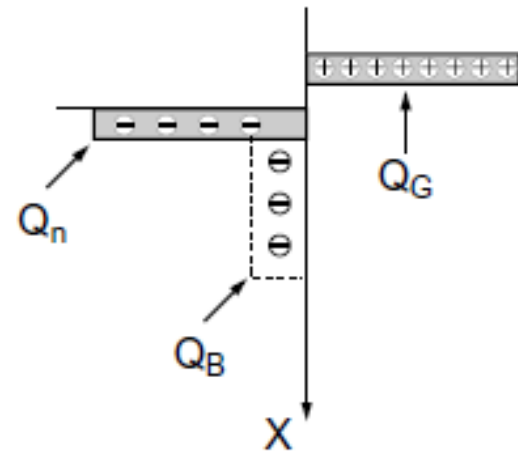
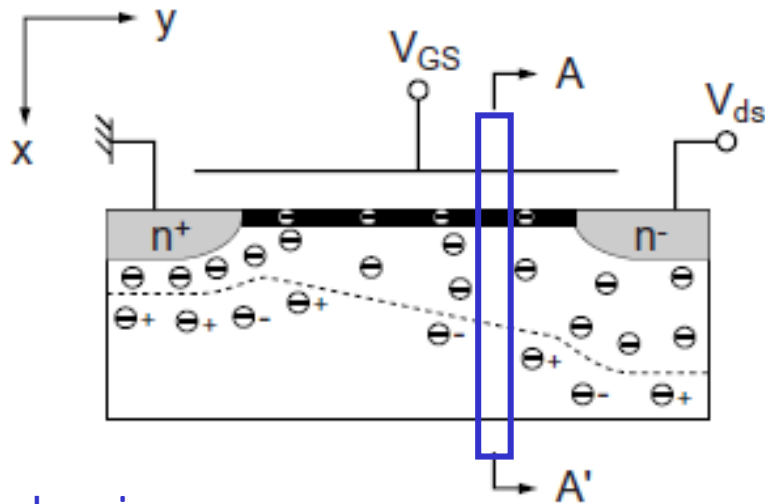
Charges and Channel



Summary of MOSFET Operation

- 1) Voltage controlled device.
- 2) Can be used as a switching element.
 $I_{ds} = 0$ (@ $V_{gs}' < V_{th}$), $I_{ds} > 0$ (@ $V_{gs}' > V_{th}$)
- 3) I_{ds} is characterized based on parabolic-curves, $I_{ds} \propto V_{gs}^2$ at Saturation operation.
- 4) Bi-directional
Symmetry even if source and drain are reversed.
→ Can be used as transfer gate (ideal switch)

Try! Physical I-V model Formulation: Gradual channel approximation



$$Q_G = Q_n + Q_B$$

$$Q_G \gg Q_B$$

The basics are:

- Capacitor equation (How many free electrons?):
- Lateral drift current (How fast they move?):

$$Q_n = CV$$

$$I = Q_n \cdot v = Q_n \mu E$$

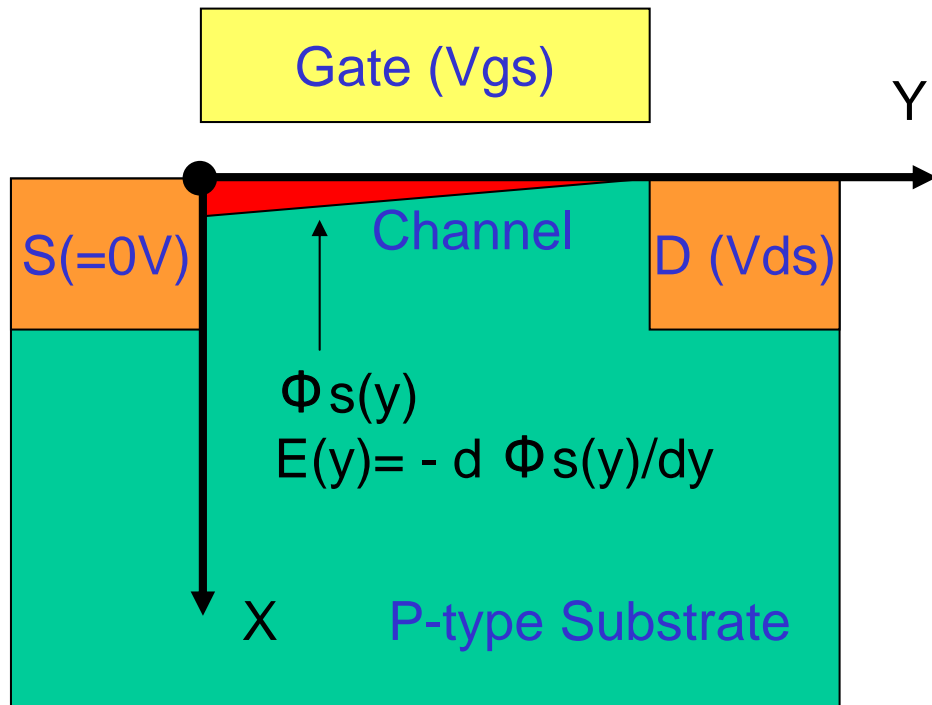
1) Capacitance Equation

$$Q_n = Q_G - Q_B \doteq -C_{ox} (V_{GS}' - \phi_s),$$

2) Drift current

$$I_{ds} = Q_n \mu W E(y), \quad \text{Here } W \text{ is channel width}$$

Some mathematics (Important!)



$\Phi_s(y)$: Channel potential @ $Y=y$
 $E(y)$: Electric field in the channel

$$I_{ds} = Q_n \mu_n W E_y$$

$$Q_n = -C_{ox} (V_{GS}' - \phi_s)$$

$$V_{GS}' = V_{GS} - V_{th}$$

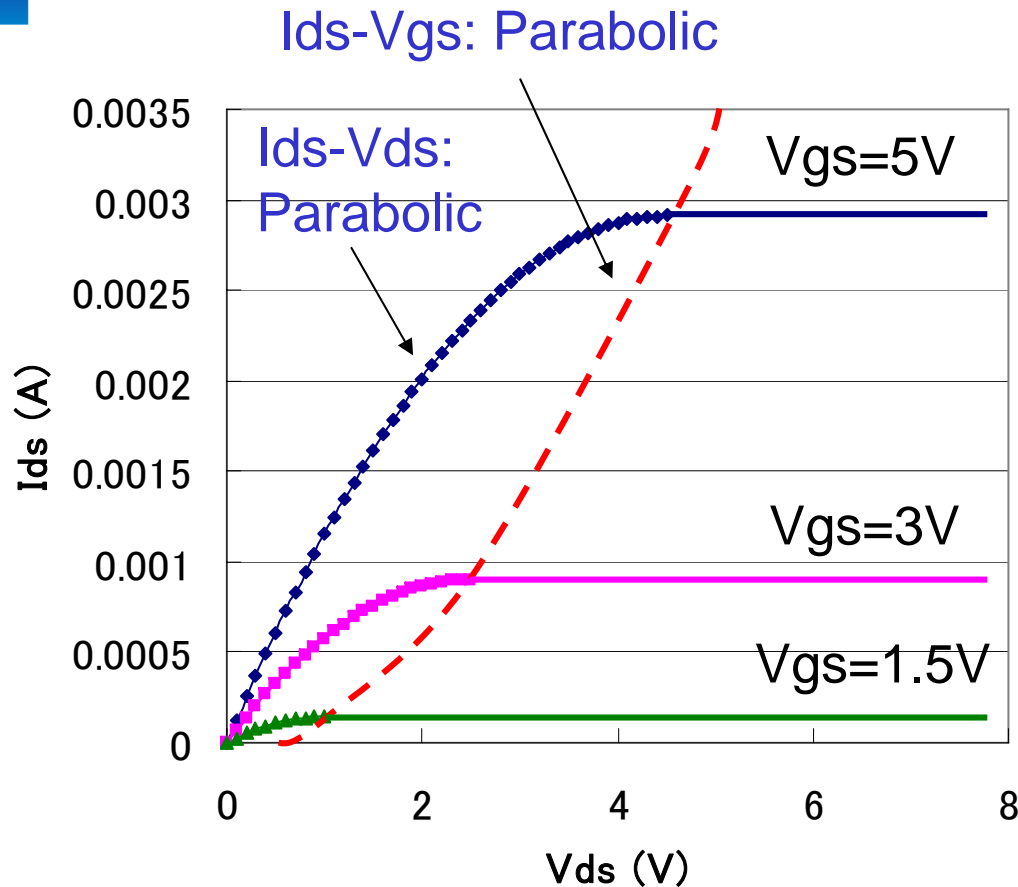
$\phi_s(y)$: Channel surface potential at y

$$I_{ds} = C_{ox} \mu W (V_{GS}' - \phi_s) \frac{d\phi_s}{dy}$$

$$I_{ds} dy = C_{ox} \mu W (V_{GS}' - \phi_s) d\phi_s$$

$$\int_0^L I_{ds} dy = C_{ox} \mu W \int_0^{V_{ds}} (V_{GS}' - \phi_s) d\phi_s$$

Continued ...



@ 1μm NMOS technology
 $L=1\mu m$, $W=5\mu m$, $T_{ox}=30nm$,
 $\mu_{eff}=500cm^2/V.sec$, $V_{gs}=1.5, 3, 5V$, $V_{th}=0.5V$

The integration results in:

$$L I_{ds} = C_{ox} \mu W (V_{GS}' V_{ds} - \frac{V_{ds}^2}{2})$$

$$I_{ds} = \frac{W}{L} C_{ox} \mu (V_{GS}' V_{ds} - \frac{V_{ds}^2}{2})$$

This is the basic MOSFET I-V Equation.

Schematic view of the I-V characteristics shows a parabolic based curve (see left Figure).

MOSFET characteristics are Parabolic Form!

We know;

I_{ds} - V_{ds} curves

I_{ds} - V_{gs} curves

they are all parabolic!

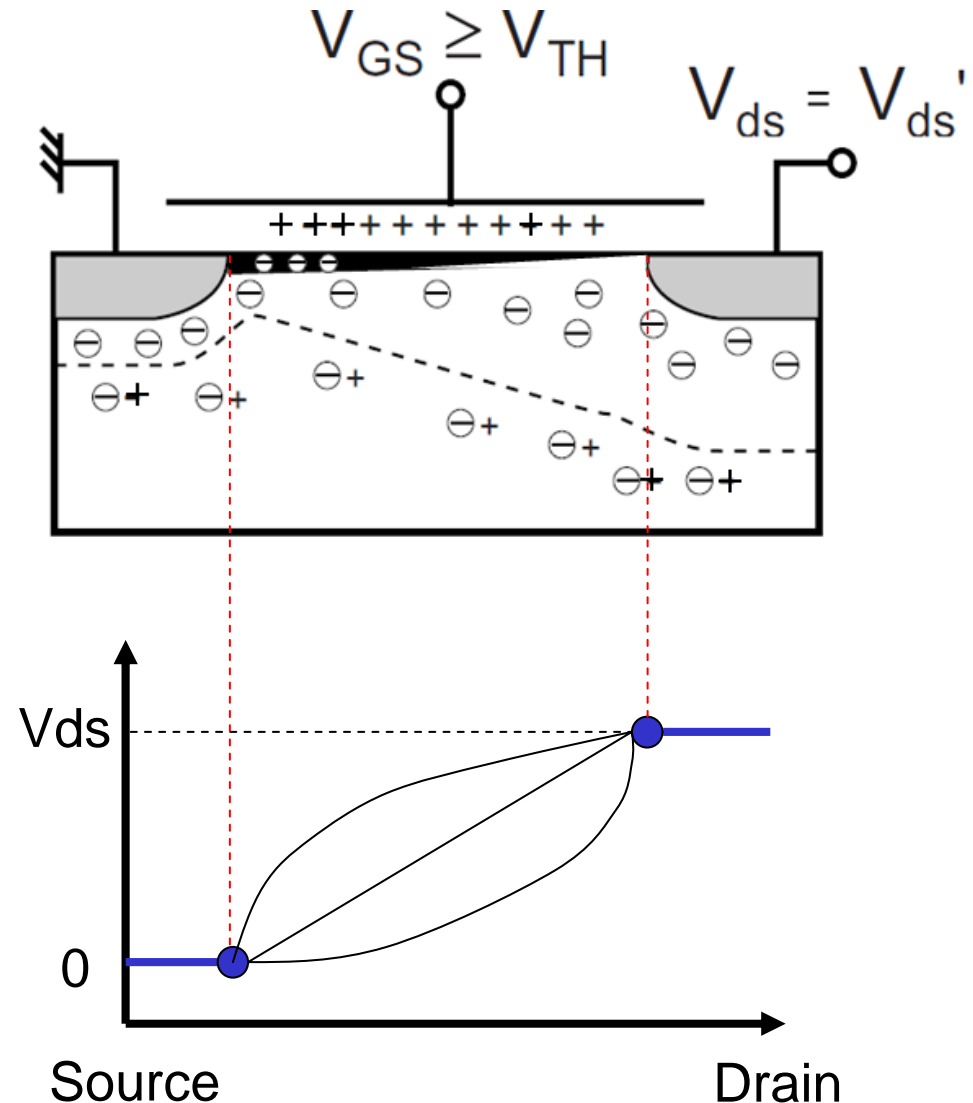
Quiz:

How about channel potential distribution between source and drain? How it looks like?

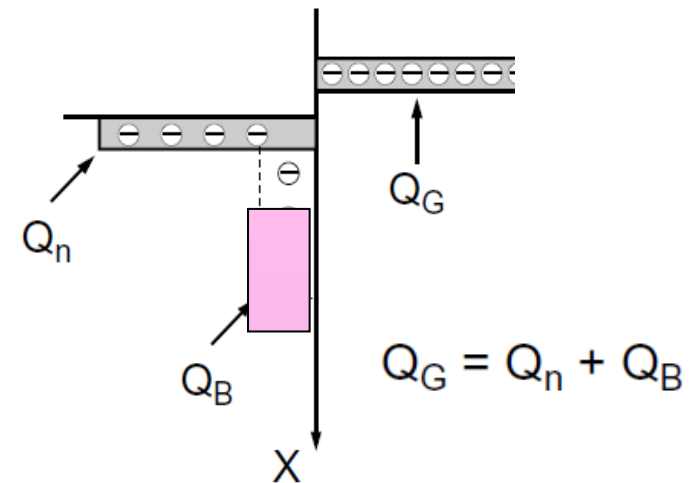
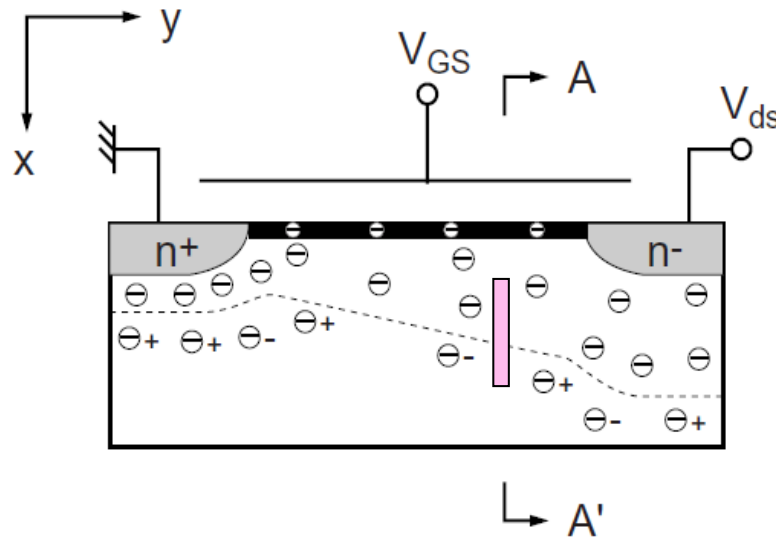
(@ saturation condition)

Answer:

It is also Parabolic!



physical I-V Model with bulk charge effect: (Hofstein model)



A-A' charge diagram

In the Simple model, we neglect bulk charge (Q_B).
More accurate approach is to consider the bulk charge.
It brings a new charge equation as follow:

$$Q_n = Q_G - Q_B = \underbrace{-C_{ox}(V_G' - \phi_s)}_{Q_G} + \underbrace{\text{[Pink Box]}}_{Q_B \text{ (Depletion layer charge)}}$$

MOSFET I-V characteristics

By using similar derivation process, we can get the I-V equation, as follow:

$$I_{ds} = -Q_n \mu_n W E_y$$

$$= \mu W \left[C_{ox} (V_{G'} - \phi_s) - \sqrt{2\epsilon_s q N_A} \sqrt{\phi_s + 2\phi_F} \right] \frac{d\phi_s}{dy}$$

$$\int_0^L I_{ds} dy = \mu W C_{ox} \int_0^{V_d} \left[(V_{G'} - \phi_s) - K_b \sqrt{\phi_s + 2\phi_F} \right] d\phi_s$$

\therefore

$$I_{ds} = C_{ox} \mu \frac{W}{L} \left\{ (V_{GS'} - \frac{V_d}{2}) V_d - \frac{2}{3} K_b \left[(V_d + 2\phi_F)^{\frac{3}{2}} - (2\phi_F)^{\frac{3}{2}} \right] \right\}$$

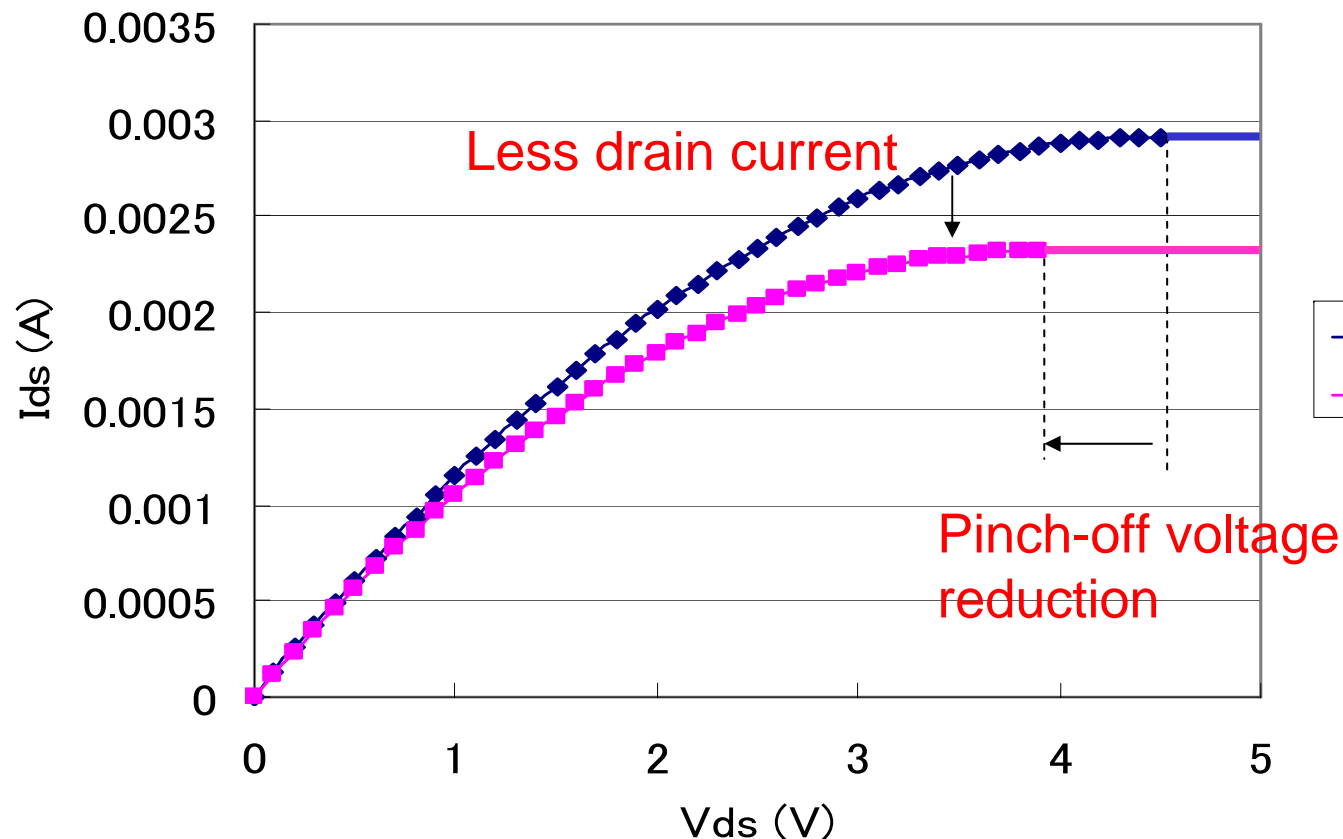
$$K_b \equiv \frac{\sqrt{2\epsilon_s q N_A}}{C_{ox}}$$

Bulk charge effect

:Substrate bias effect coefficient

How different ? with taking into account “bulk charge”

“With bulk charge” model is more accurate physically:
It results in an early pinch-off voltage and less drain current



@ 1 μ m NMOS technology
 $L=1\mu$ m, $W=5\mu$ m, $T_{ox}=30$ nm
 $\mu_{eff}=500\text{cm}^2/\text{V}\cdot\text{sec}$, $K_b=0.5$
 $V_{gs}=5\text{V}$, $V_{th}=0.5\text{V}$

Show Time on I-V Characteristics!

MOSFET Operation

Electrons

Band Structure

I-V Characteristics

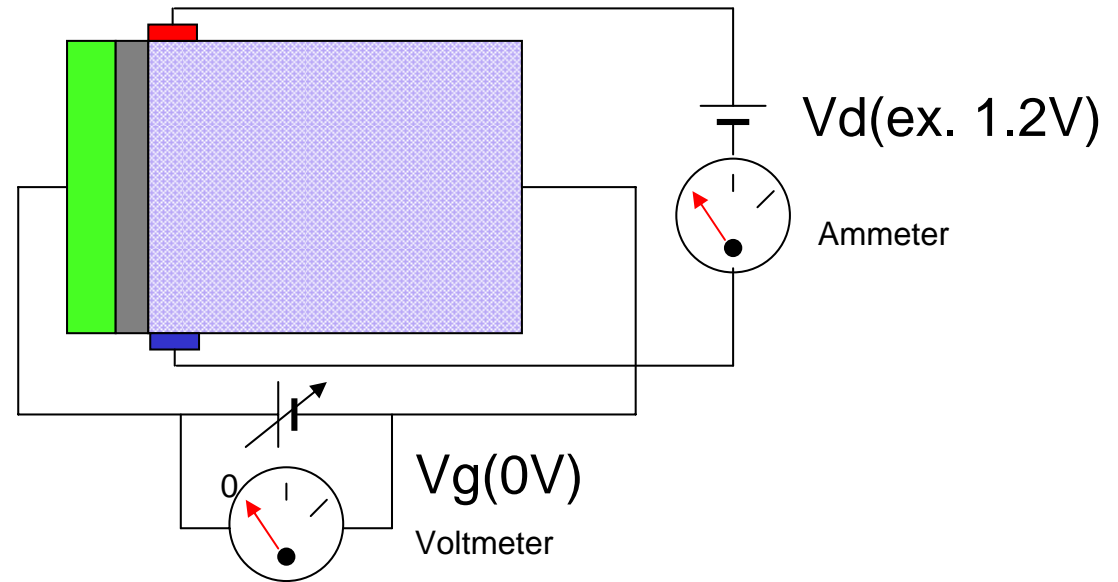
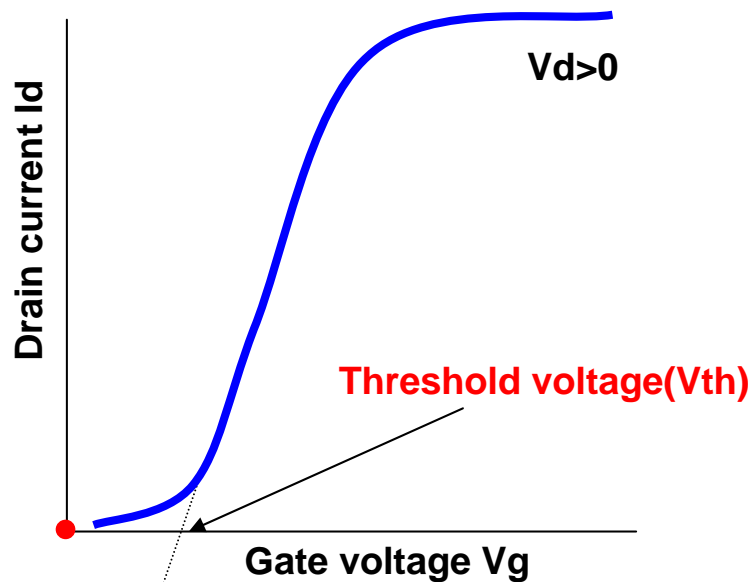
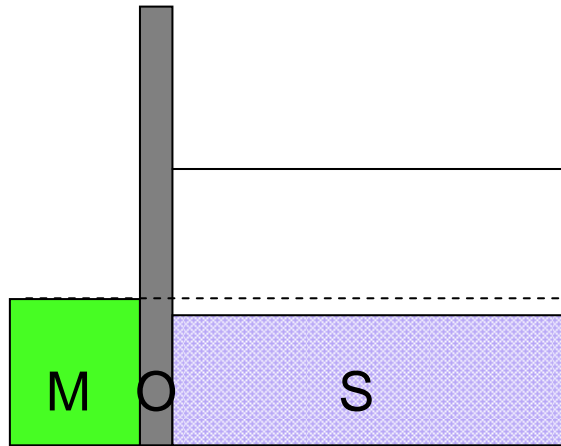
The above physical quantities are changed by:

Gate Bias Voltage = V_g

Drain Bias Voltage = V_d

Operation of N-channel MOS(NMOS)FET

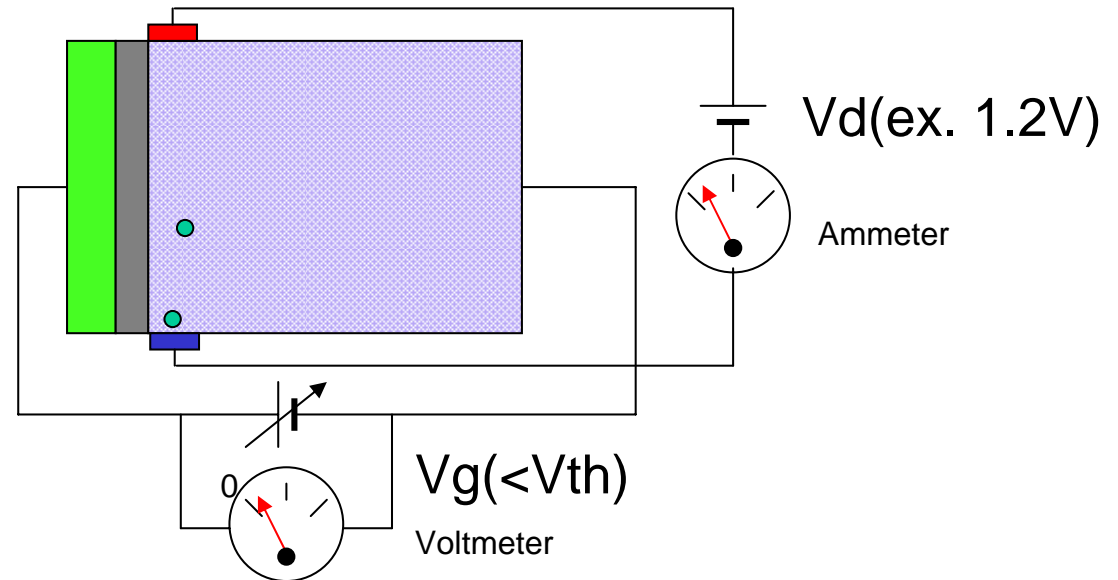
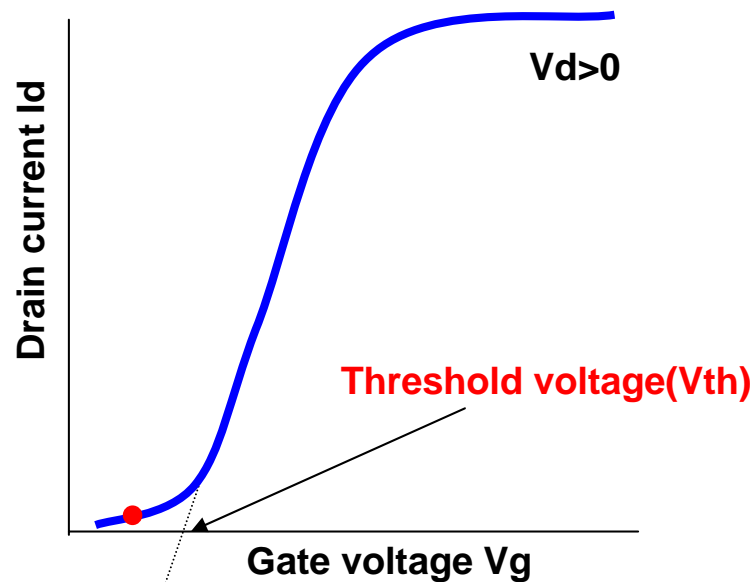
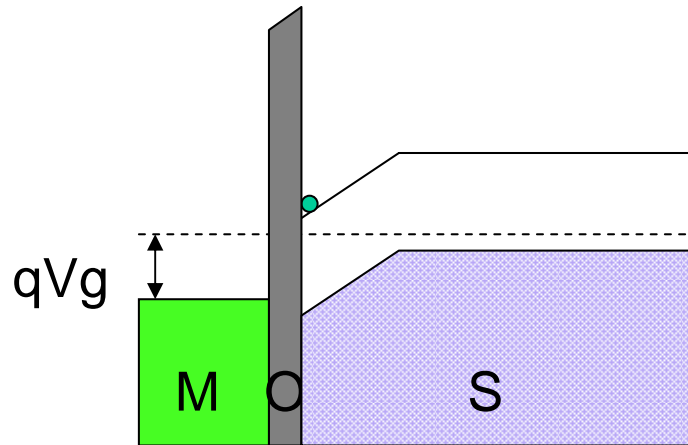
- Gate characteristics: I_d - V_g characteristics



OK, we will see what happen when gate voltage is increased @ $V_{ds}=1.2V$.

Operation of N-channel MOS(NMOS)FET

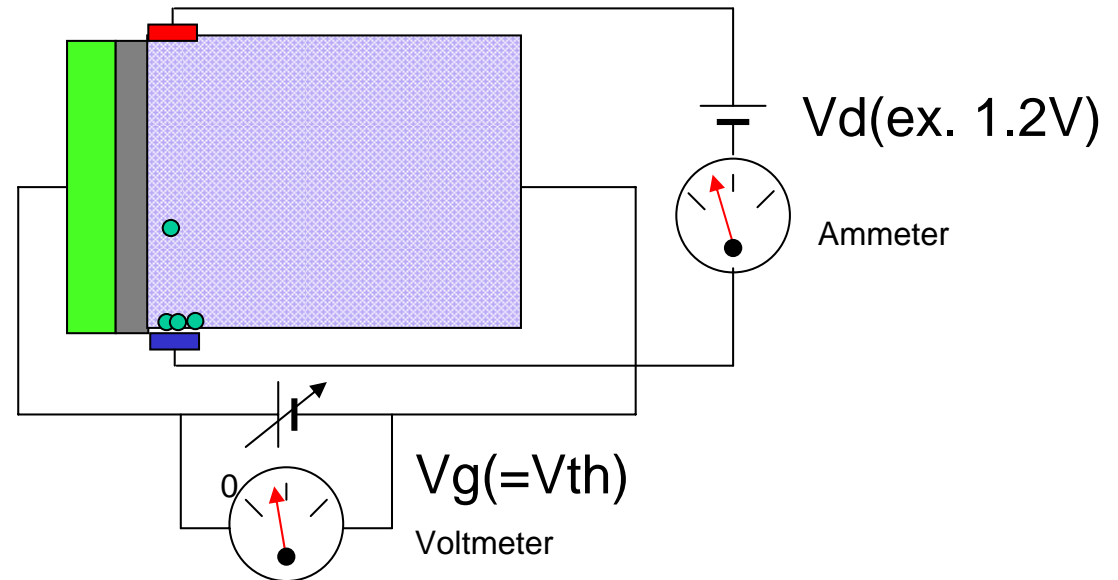
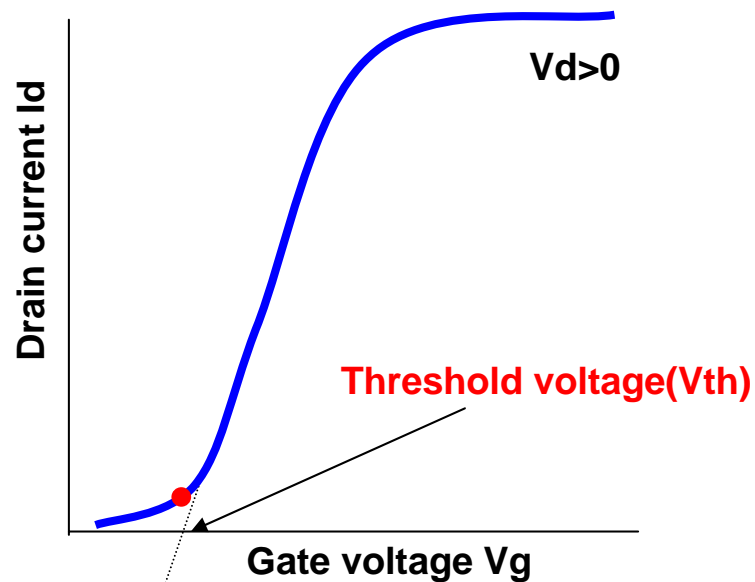
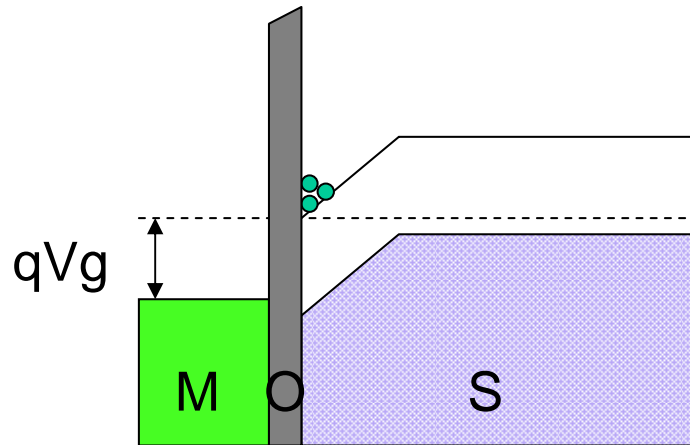
- Gate characteristics ($V_{gs} < V_{th}$)



The current under $V_{gs} < V_{th}$ is called sub-threshold current.
This is one of leakage currents.

Operation of N-channel MOS(NMOS)FET

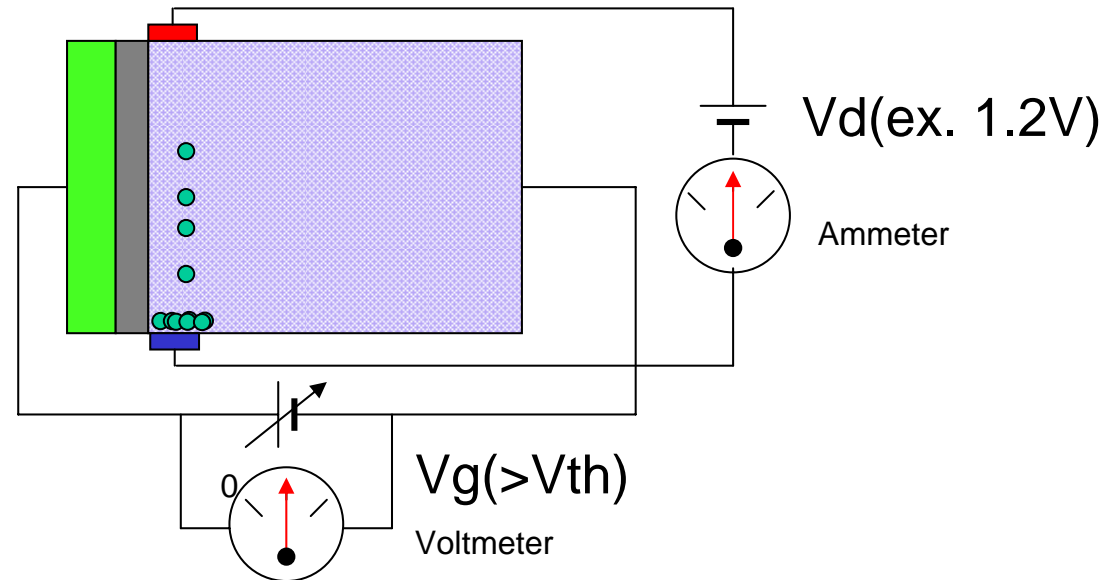
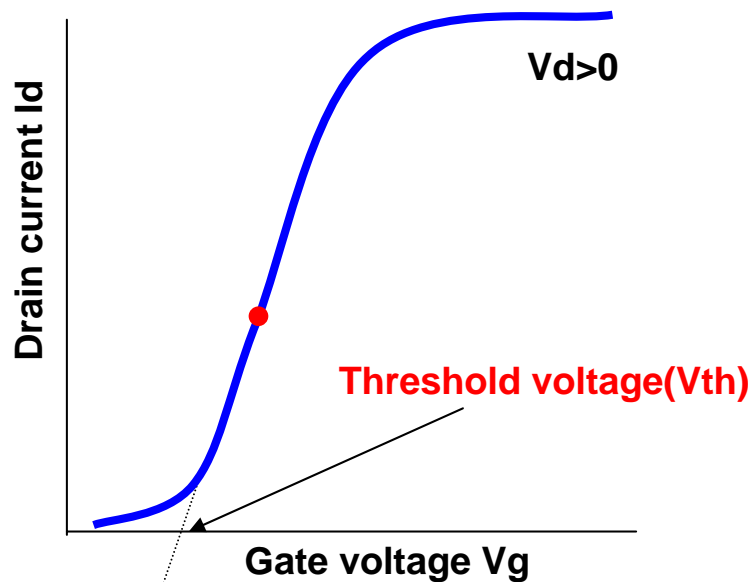
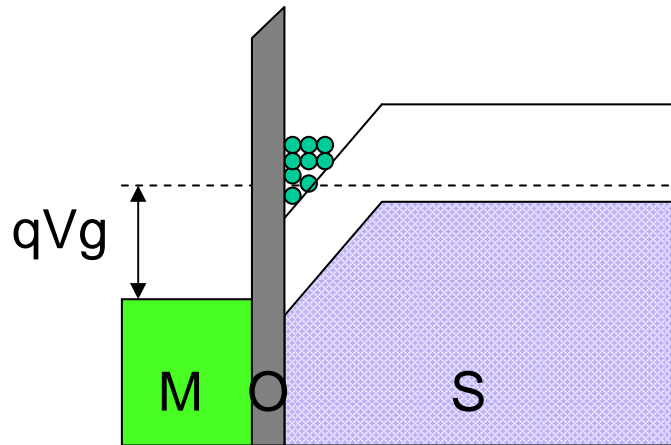
- Gate characteristics ($V_{gs}=V_{th}$)



When gate is biased at V_{th} , leak-current of $0.1\mu A$ -order does flow between source and drain. (for $L=W$ square NMOS)

Operation of N-channel MOS(NMOS)FET

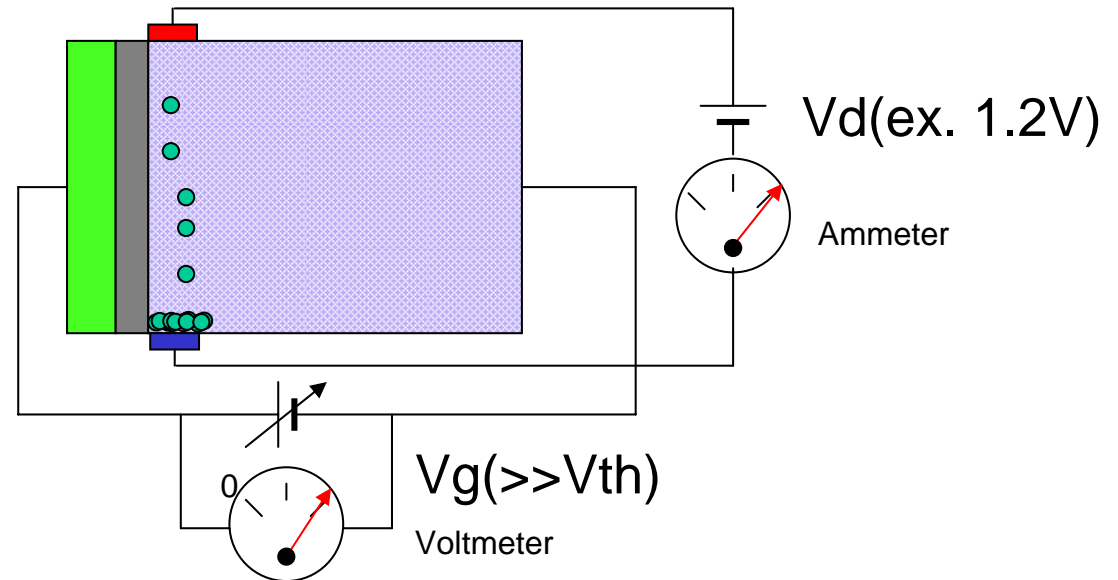
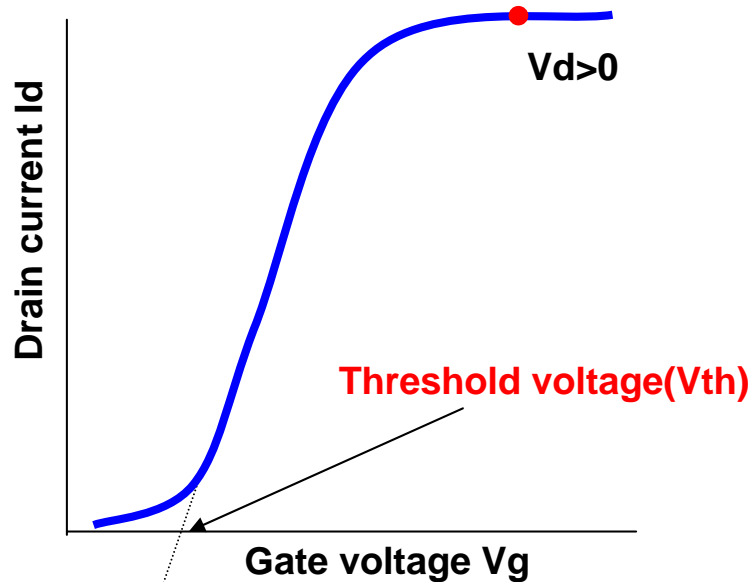
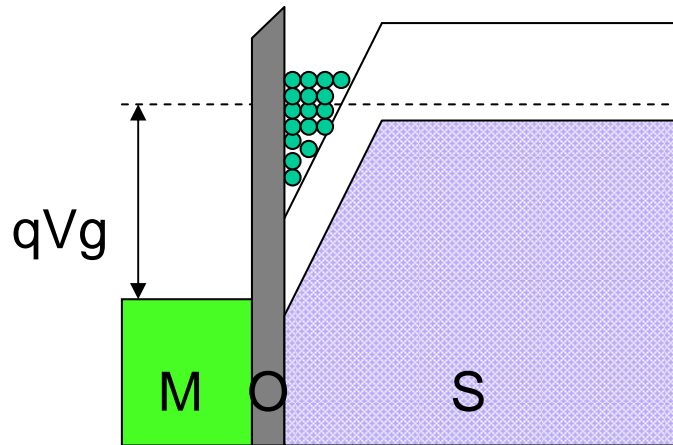
- Gate characteristics ($V_{gs} > V_{th}$)



When gate is biased above the V_{th} , drain current increases sharply in proportion to $(V_{gs} - V_{th})^2$.

Operation of N-channel MOS(NMOS)FET

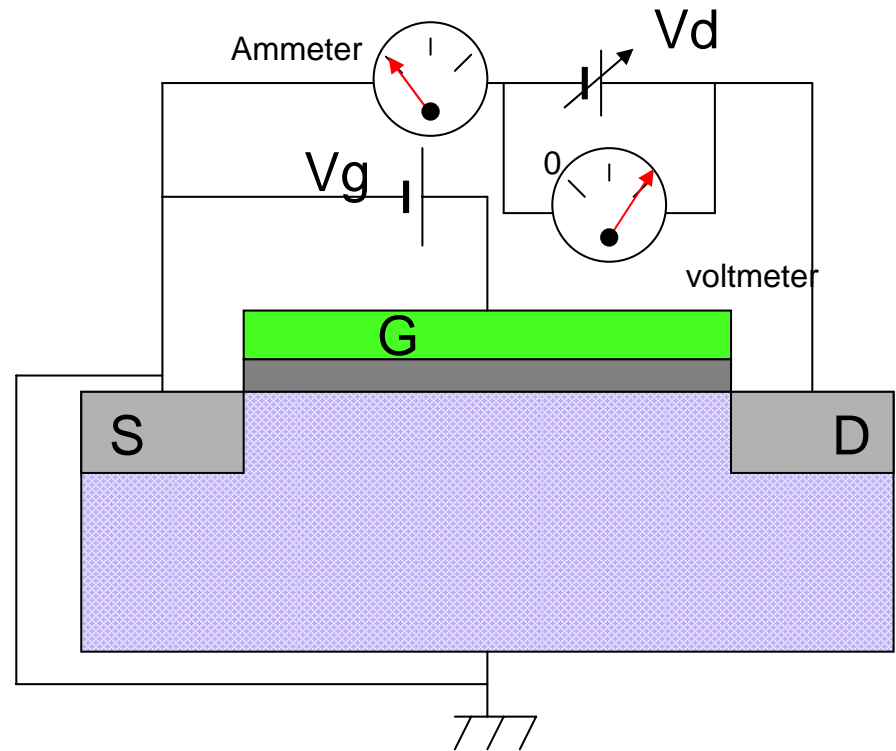
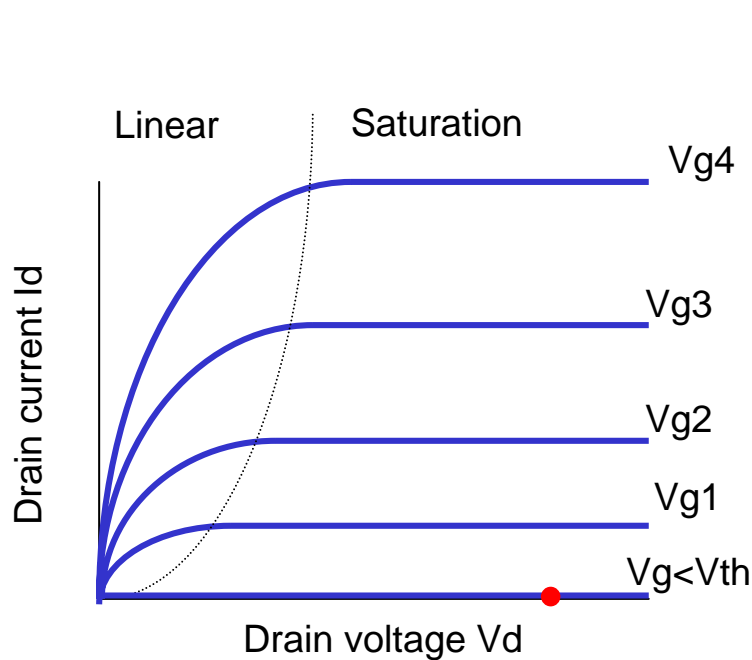
- Gate characteristics ($V_{gs} \gg V_{th}$)



However the gate is biased high enough, carrier velocity saturates due to high drain field effect. It limits increase of drain current.

Operation of N-channel MOS(NMOS)FET

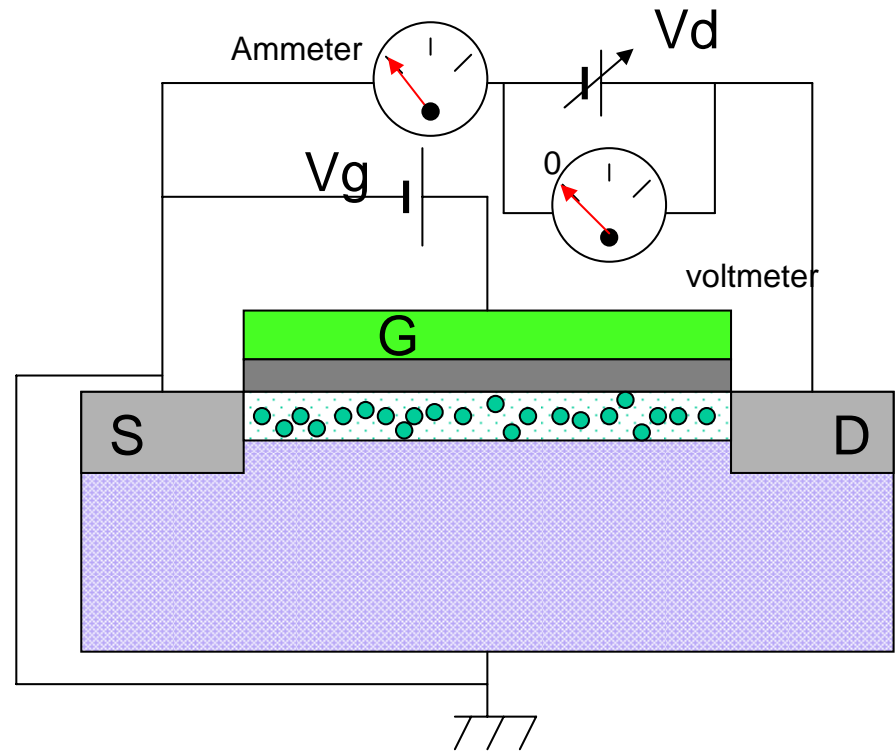
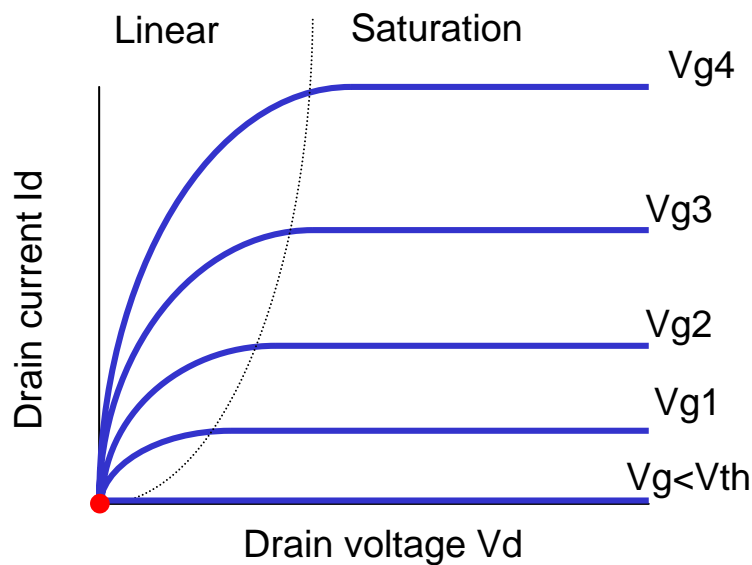
- Drain characteristics : I_d - V_d characteristics



When $V_{gs}=0 < V_{th}$, even if $V_{ds} > 0$, there is no current flows (except leakage).

Operation of N-channel MOS(NMOS)FET

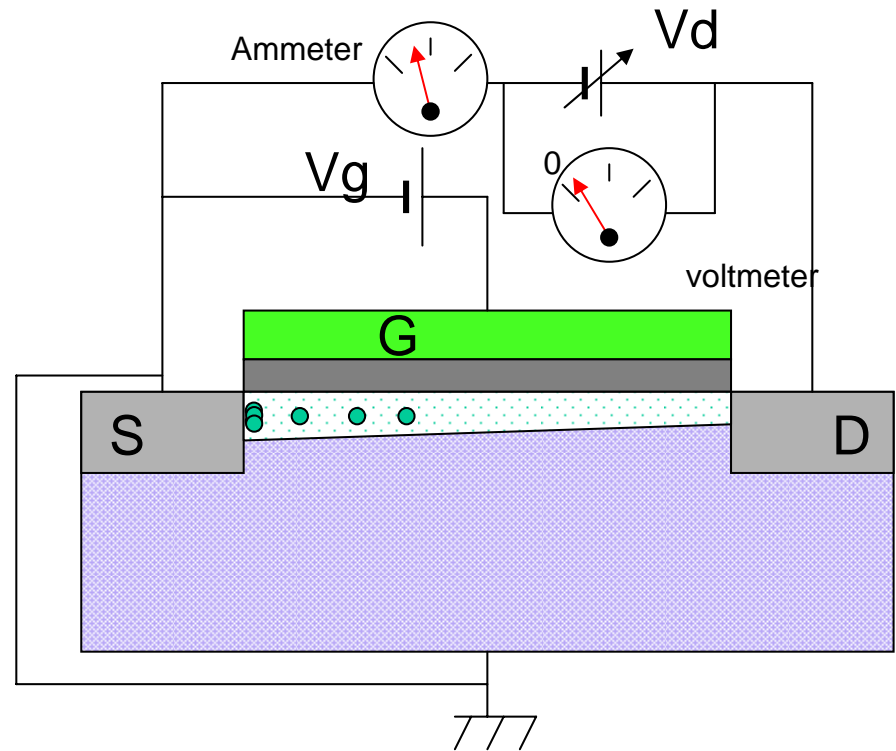
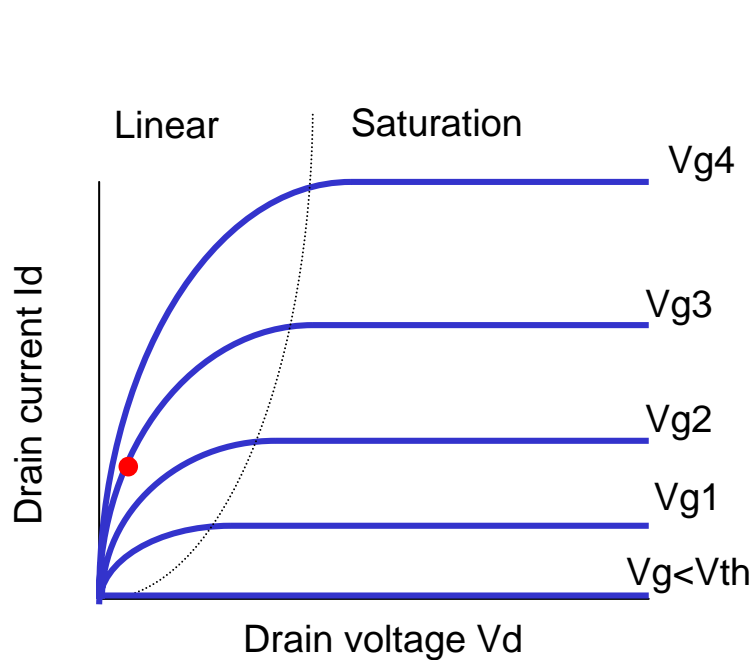
- Drain characteristics: $V_{gs}=V_{g3}$, $V_{ds}=0$



Apply $V_g=V_{g3}$ and see what happens, when you increase V_{ds} .
Now, $V_{ds}=0V$

Operation of N-channel MOS(NMOS)FET

- Drain characteristics: $V_{gs}=V_{g3}$, $V_{ds} \geq 0$



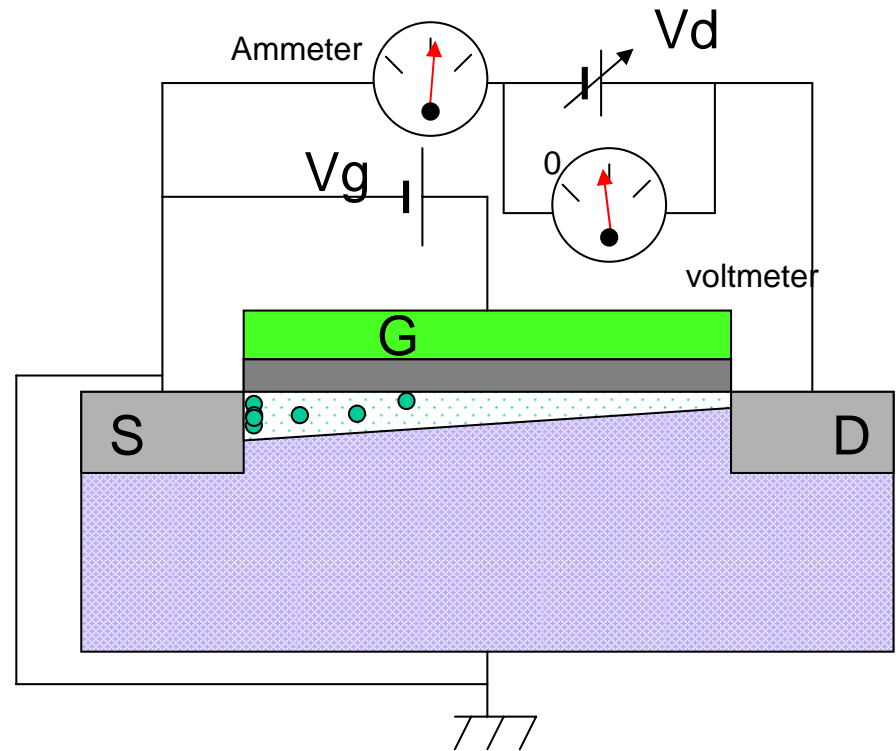
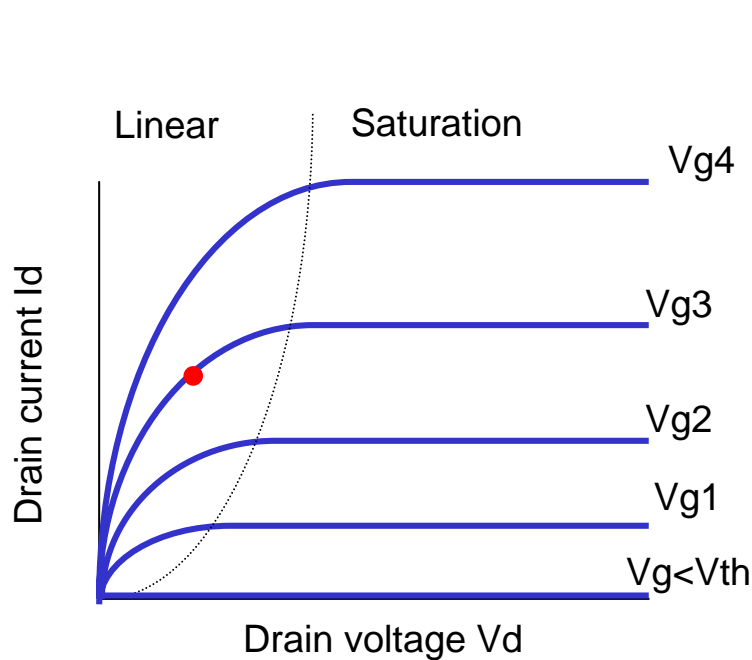
Apply small drain bias V_{ds} !

You can get quick rise in drain current.

Thickness of channel looks same along source and drain

Operation of N-channel MOS(NMOS)FET

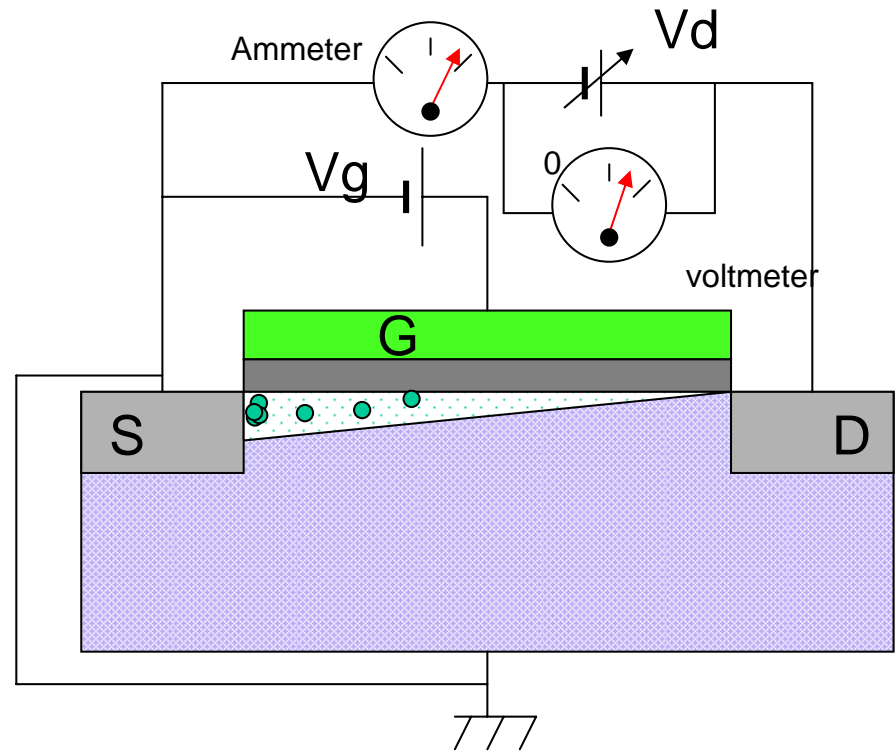
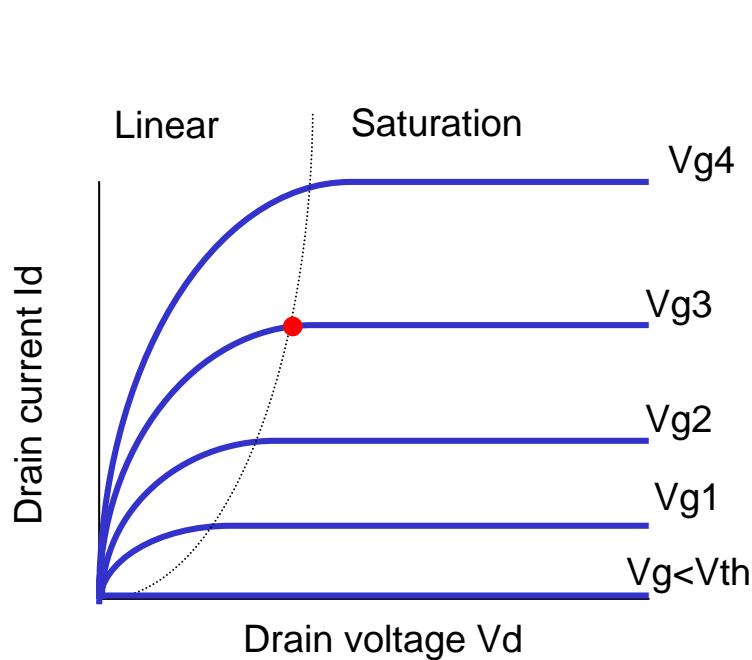
- Drain characteristics : $V_{gs}=V_{g3}$, $V_{ds} \gg 0$



Further increase of V_{ds} ! What happen in current and channel thickness?
Drain current has started to leveled-off!
Thickness of channel; channel thickness at drain edge become thinner!

Operation of N-channel MOS(NMOS)FET

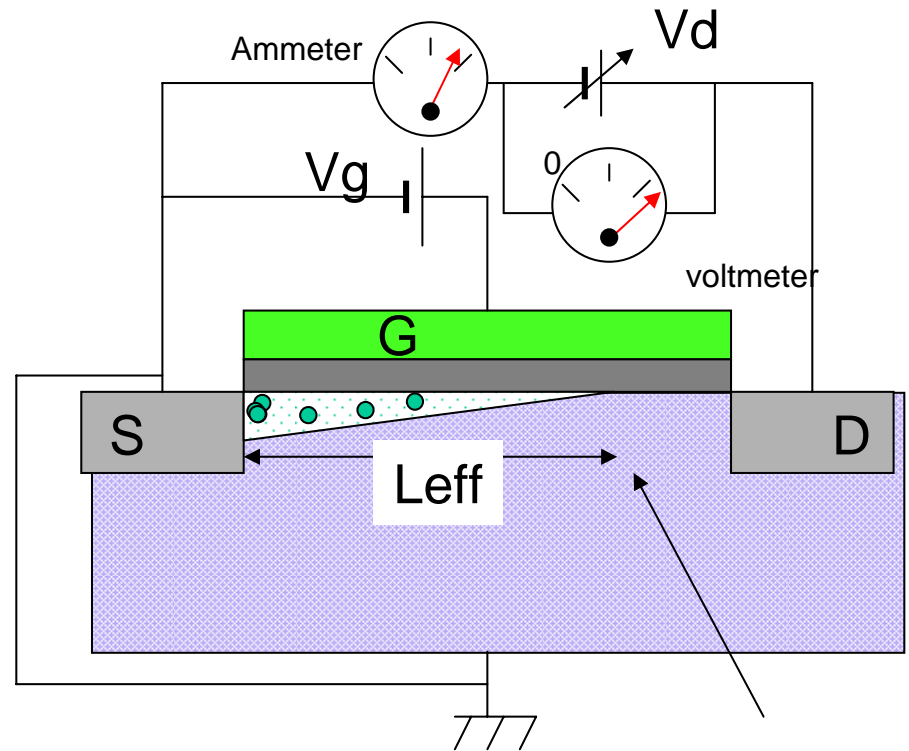
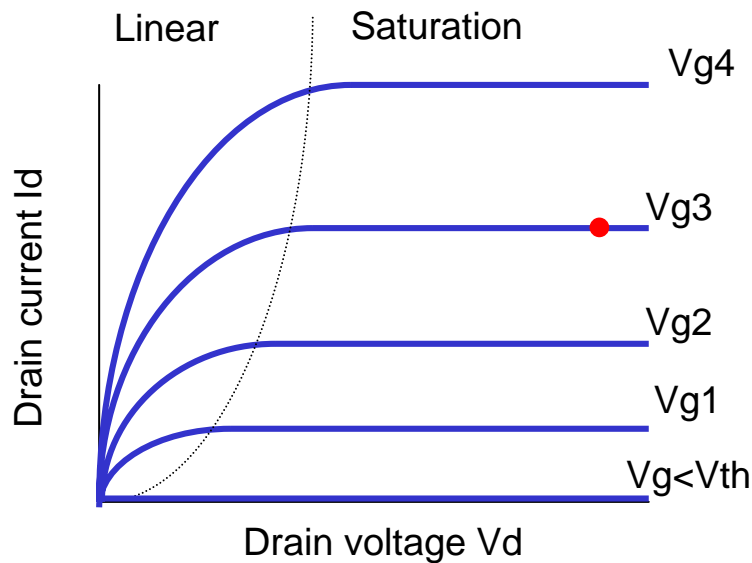
- Drain characteristics : $V_{gs}=V_{g3}$, $V_{ds}=V_{gs}-V_{th}$



When $V_{ds}=V_{gs}-V_{th}$, this situation is called “Pinch-off condition”!
Because drain current was saturated (drain conductance = 0), and the channel at drain-end has disappeared (its thickness = 0)!

Operation of N-channel MOS(NMOS)FET

- Drain characteristics : $V_{gs}=V_{g3}$, $V_{ds}>V_{gs}-V_{th}$



After the pinch-off, the drain current becomes constant.
Electrons are swept-out from the pinched channel to Drain,
and flow through the depletion region.

Summary of basic MOSFET & I-V Characters

MOSFET is ideal device for LSI:

- Small size

- Easy to isolate each others in highly integrated MOSFETs

- Capacitive input allows direct circuit connections

- Others:

 - Low power (CMOS)

 - Easy to shrink sizes (Scaling)

 - Will be discussed later

MOSFET I-V Characteristics:

- Parabolic voltage dependency of I_{ds} (to V_{gs} and V_{ds})

- Switching can be determined by " V_{th} "

- Current drivability is in proportion to " W/L " (geometry parameters)

Quiz

(1) What is the charged carrier in NMOS?

It flows from () to (). Current flows from () to ().

(2) What is the charged carrier in PMOS?

It flows from () to (). Current flows from () to ().

(3) When you design MOS Layout (determine L, W), How you can do to get double of drain current I_{ds} ?

(4) How you can control V_{th} of NMOS? If you want increase V_{th} by 0.1V, what is the best way to do in processing?

(5) How you can measure V_{th} ?